#### TRANSMITTAL

Electronic Version v1.1 Stylesheet Version v1.1.0

> Title of Invention

METHOD FOR CONTROLLING A PROCESS FOR FABRICATING INTEGRATED DEVICES

Application Number:

10/805136

Date:

2004-03-19

First Named Applicant: Matthew F Davis

**Confirmation Number:** 

8916

Attorney Docket Number: 8381/ETCH

I hereby certify that the use of this system is for OFFICIAL correspondence between patent applicants or their representatives and the USPTO. Fraudulent or other use besides the filing of official correspondence by authorized parties is strictly prohibited, and subject to a fine and/or imprisonment under applicable law.

I, the undersigned, certify that I have viewed a display of document(s) being electronically submitted to the United States Patent and Trademark Office, using either the USPTO provided style sheet or software, and that this is the document(s) I intend for initiation or further prosecution of a patent application noted in the submission. This document(s) will become part of the official electronic record at the USPTO.

Submitted by:	Elec. Sign.	Sign. Capacity
Keith P Taboada Registered Number: 45150	/Keith P Taboada/	Attorney

Documents being submitted

Files

us-ids

APPM8381-usidst.xml

us-ids.dtd

us-ids.xsl

Comments

fualmond

2/2/06



## **ELECTRONIC INFORMATION DISCLOSURE STATEMENT**

Electronic Version v18
Stylesheet Version v18.0

Title of Invention

METHOD FOR CONTROLLING A PROCESS FOR FABRICATING INTEGRATED DEVICES

**Application Number:** 

10/805136

**Confirmation Number:** 

8916

First Named Applicant: Matthew Davis
Attorney Docket Number: 8381/ETCH
Search string: (6566025).pn.

### **US Patent Documents**

Note: Applicant is not required to submit a paper copy of cited US Patent Documents

init	Cite.No.	Patent No.	Date	Patentee	Kind	Class	Subclass
	1	6566025	2003-05-20	McStravick et al.	B1		

# Signature

Examiner Name	Date
( an als mores	2/2/06

Sheet 1 of 1 sheet(s)

U.S. Department of Commerce, Patent and Trademark Office				Docket No.		Serial No.	
(PTO Form 1449 modified)				8381/ETCH/SILICON/JB1		10/805,136	
INFORMATION DISCLOSURE STATEMENT BY APPLICANT					Applicant Davis, et al. Filing Date		Confirmation No.: 8916
(Use covered cheets if necessary)				Group			
		Examiner \	DEC 2 3 2004 👸		March 19	9, 2004	
U.S. Patent	Docu	ments	TRADE AND THE		I		
Examiner nitial		Document Number	Issue Date	Applicant(s) Name	Class	Subclass	Filing Date If Appropriate
his	A1	4,767,496	08/30/1988	Hieber	156	627	
1)	A2	5,798,529	08/25/1998	Wagner	250	492.2	
(my	A3	5,926,690	07/20/1999	Toprac et al.	438	17	
1111	A4	5,948,203	09/07/1999	Wang	156	345	
(m)	A5	6,004,706	12/21/1999	Ausschnitt et al.	430	30	
Madel	A6	6,027,842	02/22/2000	Ausschnitt et al.	430	30	
Dage	A7	6,161,054	12/12/2000	Rosenthal et al.	700	121	
1000	A8	6,245,581	06/12/2001	Bonser et al.	438	8	
Min	A9	6,424,417	07/23/2002	Cohen et al.	356	388	
11/	A10	6,486,492	11/26/2002	Su	257	48	
Mily	A11	2002/0171828	11/21/2002	Cohen et al.	356	328	07/01/2002
Foreign Pa	<u> </u>	ocuments		<u></u>			
*Examiner		Document	Date	Country	Class	Subclass	Translation
Initial		Number					YES NO
	B1						
7	B2						
OTHER AF	RT	,	<u> </u>				
*Examiner Initial		Including Author, Title, Date, Pertinent Pages, Etc.					
fin	C1	Lee, et al., "Analysis of Reflectometry and Ellipsometry Data from Patterned Structures," Characterization and Metrology for UCSI Technology: 1998 International Conference, Seiler, et al., eds., pg 331-335					
Ma	C2	Raymond, "Angle-resolved scatterometry for semiconductor manufacture,", Microlithography World, Winter 2000.					
and	C3	Toprac, A., "AMD's Advanced Process Control of Ply-Gate Critical Dimension," Proc. SPIE Vo 3882, pg 62-65, Sept, 1999.					
un	C4	Optical Metrology System," Proceedings of SPIE Vol. 4689, March 2002,					
Examiner (notroduco)							
Examiner	R: Initial		rod whether or	not citation is in conf	Date Co	onsidered ith MPEP 609	2/2/05 r; Draw line through